

**PATENT**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Application No.	:	10/826,054	Confirmation No.	9460
Applicant	:	Yao-Hwan Kao, et al.		
Filed	:	April 16, 2004		
TC/A.U.	:	3753		
Title	:	Adjustable Rinse Flow In Semiconductor Processing		
Docket No.	:	N1085-00197 (TSMC2003-0309)		
Customer No.	:	08933		

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT AND RESPONSE**

Sir:

In response to the Office Action of November 27, 2006, please amend the above-identified application as follows:

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks** begin on page 4 of this paper.